



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Tepman, et al.
Serial No.: 09/451,628
Confirmation No.: 9301
Filed: November 30, 1999
For: Integrated Modular
Processing Platform

Group Art Unit: 1763

Examiner: Luz L. Alejandro Mulero

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

| CERTIFICATE OF MAILING 37 CFR 1.8 | |
|--|---------------------------------|
| I hereby certify that this correspondence is being deposited on <u>May 15</u> , 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450. | |
| <u>5/15/2003</u> Date | <u>[Signature]</u> Signature |

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RESPONSE TO OFFICE ACTION DATED JANUARY 15, 2003

In response to the Office Action dated January 15, 2003, having a shortened statutory period for response extended one month to expire on May 15, 2003, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/4285.X1/RDE, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE CLAIMS:

Please cancel claims 2, 3, and 6 without prejudice and amend the claims as follows:

1. (Amended) An apparatus for processing substrates, comprising:
- a transfer chamber comprising two or more process access ports;